



PATENT

Customer No. 222852  
Attorney Docket No. 04329-2566-00

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: )  
SHINICHI ITO et al. ) Group Art Unit: 2823  
Application No.: 09/842,403 ) Examiner: M. Estrada  
Filed: April 26, 2001 )  
For: FILM FORMATION METHOD, )  
SEMICONDUCTOR ELEMENT )  
AND METHOD THEREOF, AND )  
METHOD OF MANUFACTURING )  
A DISK-SHAPED STORAGE )  
MEDIUM )

Commissioner for Patents  
Washington, DC 20231

TECHNICAL ACTIVITY CENTER 2800  
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MAILING DATE  
MAY 5 2003

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Sir:

AMENDMENT

In reply to the Office Action dated December 4, 2002, to which the period for reply has been extended through May 5, 2003 (May 4<sup>th</sup> being a Sunday) by a request for extension of time of two months and requisite fee payment filed concurrently herewith, please amend the application as follows:

IN THE CLAIMS:

Please amend claims 1, 2, and 4, as follows:

1. (Amended) A method of forming a solution film on an in-process substrate by using a dropping section for dropping liquid and an in-process substrate just under said dropping section, maintaining the liquid dropped from said dropping section on said